



Pulse Electroplating of Ultra-Fine Grained Au Films with High Strength for Micro-Electrical-Mechanical System Devices

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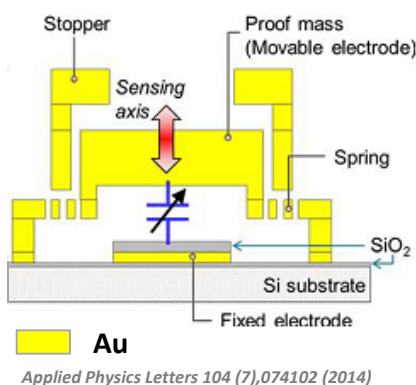
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Introduction

First MEMS Motion Sensor with Au Micro-Components



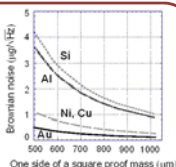
Applied Physics Letters 104 (7), 074102 (2014)

Advantage of Au

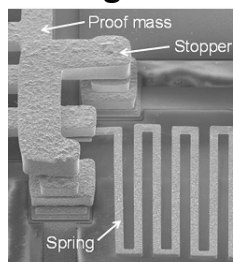
- ❖ High chemical stability
- ❖ High electrical conductivity
- ❖ Higher density than Si
Au ($19.3 \times 10^3 \text{ kg/m}^3$) >> Si ($2.33 \times 10^3 \text{ kg/m}^3$)

Merits of Au Components

- ❖ Brownian noise ↓
- ❖ Size of Sensor ↓
- ❖ Sensitivity ↑



Background



- ❖ Proof mass and spring are **movable** components
- Structure **stability** and **reliability** issues
- ❖ Lack of mechanical properties in micro-scale due to the **size effect**
- ❖ Bulk Au is **soft**, and typical yield strength of bulk Au estimated is **55-220 MPa**
- Improvement of the mechanical properties via structure control.

Journal of the Mechanics and Physics of Solids 52, 667 (2004)

In this Study

Hall-Petch relationship

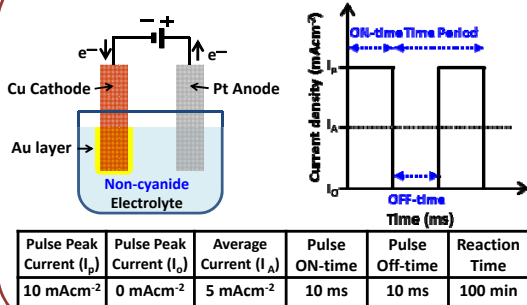
$$\sigma_y \uparrow = \sigma_0 + \frac{k_y}{\sqrt{d}}$$

Strengthening Au materials by **reducing** the grain size

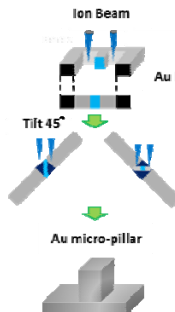
σ_y : Yield stress
 σ_0 : Materials constant for the starting stress for dislocation
 k_y : Strengthening coefficient
 d : Average grain diameter

Experimental Section

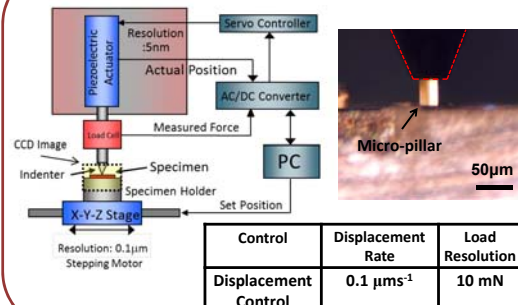
Pulse Electroplating (PE)



Micro-pillar Fabrication



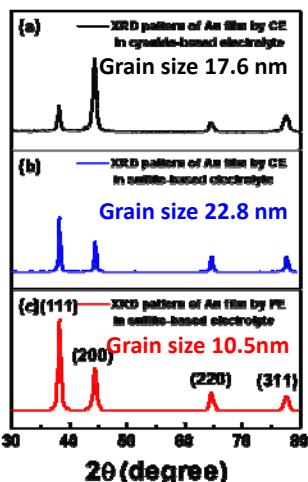
Micro Compression Test



Au Film Characterization

XRD Pattern of Au Films

AFM images & Roughness



Surface Roughness
 $R_a = 117.1 \text{ nm}$ (CE-1)

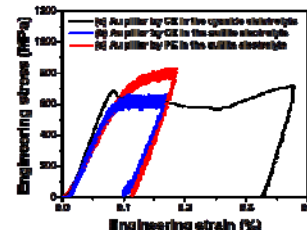
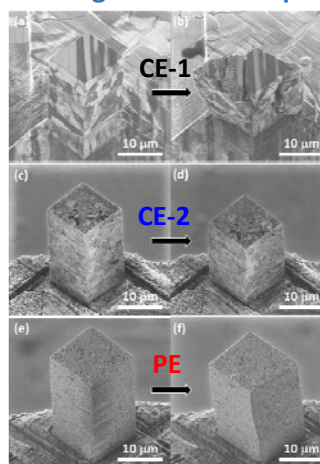
Surface Roughness
 $R_a = 32.5 \text{ nm}$ (CE-2)

Surface Roughness
 $R_a = 10.7 \text{ nm}$ (PE)

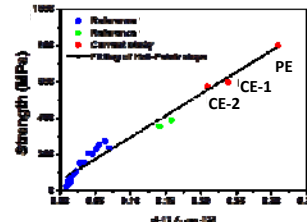
Results of Micro Compression Test

SIM Image of Au Micro-pillars

Stress-Strain Curves



Hall-Petch Plot



Summary: Grain refinement, surface smoothening, and compressive strength enhancement of Au films were achieved by pulse electroplating using sulfite-based electrolyte. The strengths obtained by PE followed the Hall-Petch relationships and reached **800MPa**, which is the highest value reported for electrodeposited pure Au when compared with the literatures.

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